**INFORMATION
DISCLOSURE
STATEMENT**

Atty. Docket No.: 110.01420101

Serial No.: 09/691,006

Applicant(s): James R. Leger et al.

Filing Date: October 18, 2000

Group: 2877

U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Name	Class	SubClass	Filing Date If Appropriate
100	5,042,951	08/27/91	Gold et al.			
100	5,910,841	06/08/99	Masao			
100	5,963,326	10/05/99	Masao			

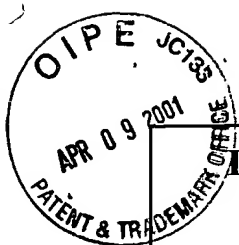
FOREIGN PATENT DOCUMENTS

	Document Number	Date	Country	Class	SubClass	Translation	
						Yes	No
	NONE						

OTHER DOCUMENTS (Including Authors, Title, Date, Pertinent Papers, etc.)

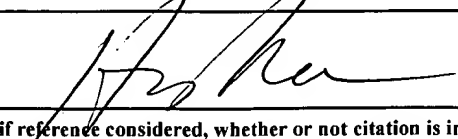
100		Albersdorfer et al., "High resolution imaging microellipsometry of soft surfaces at 3 μ m lateral and 5 Å normal resolution", <u>Appl. Phys. Lett.</u> , 72(23):2930-2932 (1998).
100		Azzam et al., "Ellipsometry and Polarized Light", Amsterdam, North Holland Physics Publishing (1988).
100		Beam Profile Ellipsometry (BPE). Therna-wave [retrieved on 2001-01-15]. Retrieved from the Internet: <URL: http://www.thermawave.com/technology/bpe.htm >, 1 page.
100		Chou et al., "Subwavelength amorphous silicon transmission gratings and applications in polarizers and waveplates", <u>Appl. Phys. Lett.</u> , 67(6):742-744 (1995).
100		Cohn et al., "Dynamic imaging microellipsometry: theory, system design, and feasibility demonstration", <u>Applied Optics</u> , 27(22):4664-4671 (1988).
100		Erman et al., "Spatially resolved ellipsometry", <u>J. Appl. Phys.</u> , 60(3):859-873 (1986).
100		Jin et al., "Imaging ellipsometry revisited: Developments for visualization of thin transparent layers on silicon substrates", <u>Rev. Sci. Instrum.</u> , 67(8):2930-2935 (1996).

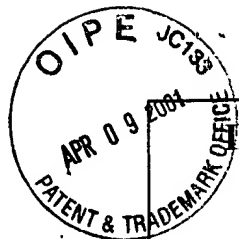
EXAMINER 	Date Considered 7/1/02
<small>*Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>	

RECEIVED
10 20 2001
CENTER 2800

INFORMATION DISCLOSURE STATEMENT	Atty. Docket No.: 110.01420101	Serial No.: 09/691,006
	Applicant(s): James R. Leger et al.	
	Filing Date: October 18, 2000	Group: 2877

100		I-Elli2000 Imaging Ellipsometer. Nano-film Technologie [retrieved on 2001-01-15]. Retrieved from Internet: <URL: http://www.nanofilm.ed/html/elli2000/body_i-elli2000.html >, 16 pages.
100		Imaging Ellipsometer. Beaglehole Instruments [retrieved on 2001-01-15]. Retrieved from Internet: <URL: http://www.beaglehole.com/imelli/im-main.html >, 9 pages.
100		Karlsson, "Detector and Data Acquisition System for an Imaging Ellipsometer", IEEE Instrumentation and Measurement Technology Conference, St. Paul, Minnesota, USA, May 18-21, 1998, 1:679-682 (1998).
100		Leng et al., "Characterization of titanium nitride (TiN) films on various substrates using spectrophotometry, beam profile reflectometry, beam profile ellipsometry and spectroscopic beam profile ellipsometry", <u>Thin Solid Films</u> , 313-314:308-313 (1998).
100		Leng et al., "Combined beam profile reflectometry, beam ellipsometry and ultraviolet-visible spectrophotometry for the characterization of ultrathin oxide-nitride-oxide films on silicon", <u>J. Vac. Sci. Tech.</u> , A17(2):380-384 (1999).
100		Liu et al., "Image scanning ellipsometry for measuring nonuniform film thickness profiles", <u>Applied Optics</u> , 33(7):1223-1229 (1994).
100		Logofatu et al., "Identity of the cross-reflection coefficients for symmetric surface-relief gratings", <u>J. Opt. Soc. Am. A</u> , 16(5):1108-1114 (1999).
100		Mansfield et al., "Solid immersion microscope", <u>Appl. Phys. Lett.</u> , 57(24):2615-2616 (1990).
100		Mansuripur, "Certain computational aspects of vector diffraction problems", <u>J. Opt. Soc. Am. A</u> , 6(5):786-805 (1989).
100		Mansuripur, "Distribution of light at and near the focus of high-numerical-aperture objectives", <u>J. Opt. Soc. Am. A</u> , 3(12):2086-2093 (1986).
100		Nordin et al., "Broadband form birefringent quarter-wave plate for the mid-infrared wavelength region", <u>Optics Express</u> , 5(8):163-168 (1999).
100		Rosencwaig et al., "Beam profile reflectometry: a new technique for dielectric film measurements", <u>Appl. Phys. Lett.</u> , 60(11):1301-1303 (1992).
100		See et al., "Scanning optical microellipsometer for pure surface profiling", <u>Applied Optics</u> , 35(34):6663-6668 (1996).

EXAMINER 	Date Considered 7/17/02
*Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	



INFORMATION DISCLOSURE STATEMENT	Atty. Docket No.: 110.01420101	Serial No.: 09/691,006
	Applicant(s): James R. Leger et al.	
	Filing Date: October 18, 2000	Group: 2877

<i>AS</i>		Spesivtsev et al., "Automatic Scanning Microellipsometer", <u>Optoelectr., Instrum. and Data Process.</u> , 1:90-94 (1997).
<i>AS</i>		Tompkins et al., "Spectroscopic Ellipsometry and Reflectometry", N.Y., John Wiley & Sons, Inc. (1999).
<i>AS</i>		Ye, "Non mechanical half-wave plate polarization rotator", <u>Optik</u> , 101(2):77-79 (1995).
EXAMINER <i>AS</i>		Date Considered 07/1/02
<small>*Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</small>		

Based on Form PTO-FB-A820 Patent and Trademark Office, U.S. Department of Commerce
(Also form PTO-1449)

RECEIVED
APR 10 2001
TECHNOLOGY CENTER 2800